	Application No.	Applicant(s)
Notice of Allowability	10/767,203	HWANG, LEE-YEUN
	Examiner	Art Unit
	Handban A. Date.	2042
	Heather A. Doty	2813
The MAILING DATE of this communication app All claims being allowable, PROSECUTION ON THE MERITS IS herewith (or previously mailed), a Notice of Allowance (PTOL-85) NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT R of the Office or upon petition by the applicant. See 37 CFR 1.313	(OR REMAINS) CLOSED in or other appropriate commusing the commusing the commusing the community of the commu	this application. If not included unication will be mailed in due course. THIS
1. \boxtimes This communication is responsive to <u>the RCE and remark</u>	s dated 1/8/2007	
2. The allowed claim(s) is/are <u>1,3-14,16-21 and 23-25</u> .		
 3. Acknowledgment is made of a claim for foreign priority u a) All b) Some* c) None of the: 1. Certified copies of the priority documents have 		or (f).
		n No. 00/863 453
3. ☐ Copies of the certified copies of the priority do	• •	
International Bureau (PCT Rule 17.2(a)).	cuments have been received	in this hational stage application from the
* Certified copies not received:		
Applicant has THREE MONTHS FROM THE "MAILING DATE" noted below. Failure to timely comply will result in ABANDONN THIS THREE-MONTH PERIOD IS NOT EXTENDABLE. 4. A SUBSTITUTE OATH OR DECLARATION must be subm	MENT of this application.	
INFORMAL PATENT APPLICATION (PTO-152) which giv		
5. CORRECTED DRAWINGS (as "replacement sheets") must be submitted.		
(a) I including changes required by the Notice of Draftsper	son's Patent Drawing Review	v (PTO-948) attached
1) 🗌 hereto or 2) 🔲 to Paper No./Mail Date	<u>.</u> .	
(b) ☐ including changes required by the attached Examiner Paper No./Mail Date	's Amendment / Comment or	in the Office action of
Identifying indicia such as the application number (see 37 CFR feach sheet. Replacement sheet(s) should be labeled as such in		
6. DEPOSIT OF and/or INFORMATION about the deposit attached Examiner's comment regarding REQUIREMENT		
Attachment(s)	_	
1. Notice of References Cited (PTO-892)		formal Patent Application
2. Notice of Draftperson's Patent Drawing Review (PTO-948)		ummary (PTO-413), Mail Date
3. Information Disclosure Statements (PTO/SB/08), Paper No./Mail Date	7. ☐ Examiner's	Amendment/Comment
4. Examiner's Comment Regarding Requirement for Deposit of Biological Material		Statement of Reasons for Allowance
	9. 🗌 Other	CAPL WHITEHEAD, JR. SUPERVISORY PATENT EXAMINER TECHNOLOGY CENTER 2800

Art Unit: 2813

DETAILED ACTION

Continued Examination Under 37 CFR 1.114

A request for continued examination under 37 CFR 1.114, including the fee set forth in 37 CFR 1.17(e), was filed in this application after final rejection. Since this application is eligible for continued examination under 37 CFR 1.114, and the fee set forth in 37 CFR 1.17(e) has been timely paid, the finality of the previous Office action has been withdrawn pursuant to 37 CFR 1.114. Applicant's submission filed on 1/8/2007 has been entered.

Allowable Subject Matter

Claims 1, 3-14, 16-21, and 23-25 are allowed.

The following is an examiner's statement of reasons for allowance:

Regarding claim 1, prior art does not teach or suggest, in combination with the other claimed limitations, a first high-density diffusion layer formed on an upper portion of the first polysilicon layer, or a second polysilicon layer filling a second trench formed between the n and p-type drift regions of the gate region such that the oxide film is deposited in the second trench as well as the upper portion of the drift region corresponding to the drain region.

Regarding claims 9 and 16, prior art does not teach or suggest, in combination with the other claimed limitations, a first high-density diffusion layer formed in an upper portion of the source region including a portion of the first polysilicon layer and a portion of the first drift region in between the first trench and the gate region, or an oxide film formed in a second trench formed on an upper portion of the gate region in between the

second trench and the drain region, or a second polysilicon layer filling the second trench and covering the oxide film such that the gate electrode covers at least a portion of the second polysilicon layer and the oxide film on the upper portion of the gate region.

Regarding the rejections made in the final rejection, the examiner finds Applicant's arguments persuasive.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Conclusion

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Heather A. Doty, whose telephone number is 571-272-8429. The examiner can normally be reached on M-F, 9:30 - 2:00.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Carl Whitehead, Jr., can be reached at 571-272-1702. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For

Art Unit: 2813

more information about the PAIR system, see http://pair-direct.uspto.gov. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free). If you would like assistance from a USPTO Customer Service Representative or access to the automated information system, call 800-786-9199 (IN USA OR CANADA) or 571-272-1000.

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